



IPW

PATENT
Customer No. 22,852
Attorney Docket No. 4329.2959-01000

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
)
Gaku MINAMIHABA et al.) Group Art Unit: 1765
)
Application No.: 10/762,514) Examiner: Eric B. CHEN
)
Filed: January 23, 2004) Confirmation No.: 5239
)
For: SLURRY FOR CHEMICAL MECHANICAL)
POLISHING FOR COPPER AND METHOD)
OF MANUFACTURING SEMICONDUCTOR)
DEVICE USING THE SLURRY)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

REQUEST FOR RECONSIDERATION

In reply to the Office Action mailed October 20, 2005, please reconsider and reexamine the above-identified application in view of the Remarks that begin on page 2 of this paper.

Attachments to this Request include an English language translation of Japanese Patent Application 2001-366938, filed in Japan on November 30, 2001, and a statement of accuracy signed by the translator.